CrossMark





Conclusions

It has been demonstrated that the helium ion microscope has several unique properties that, when combined together, will allow for higher resolution imaging than that available today with conventional scanning electron microscopes. In addition to better resolution, the helium ion microscope also provides unique contrast mechanisms both in secondary electron mode and RBI mode that enable material discrimination and identification.

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ERRATA

In the article in the May 2006 issue:

Precise SEM Cross Section Polishing via Argon Beam Milling

by

N. Erdman, R. Campbell, and S. Asahina

The correct caption for figure 7 on page 25 should be:

Figure 7. Image of a yeast cell cross section.

This was communicated to me by the authors prior to printing the issue and I failed to make the correction. ... Editor

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